	Application No.	Applicant(s)	
	00/776 220		
Notice of Allowability	09/776,329 Examiner	SEUTTER ET AL. Art Unit	
·			لهم ا
	Toniae M. Thomas	2822	<u> </u>
The MAILING DATE of this communication appe All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate communication is second communication is second communication in the communication is second communication.	n this application. If not include unication will be mailed in due	ed course. <b>THIS</b>
1.   This communication is responsive to the amendment filed of	o <u>n</u> .		
2. A The allowed claim(s) is/are 4-8,16-23,32-34,38-44,56 and 6	<u>68</u> .		
3.  The drawings filed on 27 April 2001 are accepted by the Ex	kaminer.		
<ul> <li>4. ☐ Acknowledgment is made of a claim for foreign priority un</li> <li>a) ☐ All b) ☐ Some* c) ☐ None of the:</li> </ul>	der 35 U.S.C. § 119(a)-(d) o	or (f).	
<ol> <li>Certified copies of the priority documents have</li> </ol>			
<ol><li>Certified copies of the priority documents have</li></ol>	been received in Application	on No	
<ol><li>Copies of the certified copies of the priority doc</li></ol>	cuments have been received	d in this national stage applica	tion from the
International Bureau (PCT Rule 17.2(a)).		,	
* Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DATE" on noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to file ENT of this application.	e a reply complying with the re	quirements
5. A SUBSTITUTE OATH OR DECLARATION must be submi INFORMAL PATENT APPLICATION (PTO-152) which give	tted. Note the attached EXAss reason(s) why the oath or	AMINER'S AMENDMENT or Nor declaration is deficient.	OTICE OF
6. CORRECTED DRAWINGS ( as "replacement sheets") mus	t be submitted.		
(a) ☐ including changes required by the Notice of Draftspers		v ( PTO-948) attached	
1) hereto or 2) to Paper No./Mail Date	<b>3</b>	( · · · · · · · · · · · · · · · · · · ·	
(b) ☐ including changes required by the attached Examiner's Paper No./Mail Date	Amendment / Comment or	r in the Office action of	
Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the	84(c)) should be written on the header according to 37 CF	he drawings in the front (not the FR 1.121(d).	back) of
<ol> <li>DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT I</li> </ol>	sit of BIOLOGICAL MATE FOR THE DEPOSIT OF BIO	ERIAL must be submitted. I DLOGICAL MATERIAL.	Note the
Attachment(s) 1. ☑ Notice of References Cited (PTO-892)	5. Notice of In	formal Patent Application (PT	D-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)		ummary (PTO-413), /Mail Date	ŕ
<ol> <li>Information Disclosure Statements (PTO-1449 or PTO/SB/06 Paper No./Mail Date</li> </ol>		Amendment/Comment	
4. Examiner's Comment Regarding Requirement for Deposit		Statement of Reasons for Allo	wance
of Biological Material	9. 🗌 Other	_•	-
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U.S. Patent and Trademark Office		" "Inary Examine	9r

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## Reasons for Allowance

The following is an examiner's statement of reasons for allowance: the prior art of record does not anticipate or render obvious a method of film deposition substantially as claimed. While the plasma annealing of tantalum nitride is known in the art, the prior art of record does not anticipate, teach, or suggest plasma annealing a tantalum nitride, wherein tantalum and nitrogen are chemisorbed from a tantalum-containing gas and a nitrogen-containing gas, respectively, to form the tantalum nitride film, or wherein a tantalum-containing precursor and a nitrogen-containing precursor are co-reacted to chemisorb a first layer on a wafer surface. Furthermore, the prior art of record does not anticipate, teach, or suggest chemisorbing tantalum and nitrogen from a tantalum-containing gas and a nitrogen-containing gas, while maintaining the substrate above a thermal decomposition temperature of the tantalum-containing gas.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Toniae M. Thomas whose telephone number is (571) 272-1846. The examiner can normally be reached on Monday-Thursday from 8:30 a.m. to 5:30 p.m..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Amir Zarabian can be reached on (571) 272-1852. The

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fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

TMT

29 November 2004

Mary Wilczewski Primary Examiner